

Handwritten: *John*  
Docket No.: 50090-334

# 71 BEX  
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT  
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re Application of

Masanobu IWASAKI, et al.

Serial No.: 09/934,474 ✓

Filed: August 23, 2001

Group Art Unit: 3723

Examiner: H. Shakeri

For: POLISHING SOLUTION SUPPLY SYSTEM, METHOD OF SUPPLYING  
POLISHING SOLUTION, APPARATUS FOR AND METHOD OF POLISHING  
SEMICONDUCTOR SUBSTRATE AND METHOD OF MANUFACTURING  
SEMICONDUCTOR DEVICE

AMENDMENT UNDER 37 CFR §1.116

Commissioner for Patents  
Washington, DC 20231

Sir:

The following Amendment and Remarks are submitted in response to the Office  
Action dated April 18, 2002, pursuant to the provisions of 37 C.F.R. §1.116.

IN THE CLAIMS:

Please amend claims 3, 5 and 10 as follows.

3. (Twice Amended) The apparatus according to claim 1, wherein each of  
said supply units comprises:

a tank for storing liquid;

a pipe for supplying said liquid from said tank to said mixing unit;